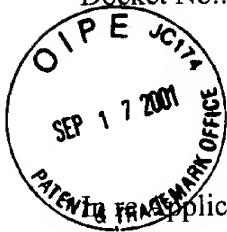


Docket No.: 50212-211



RECEIVED  
PATENT  
SEP 19 2001

TC 2800 MAIL ROOM

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of

Kenichi ARIMURA, et al.

Serial No.: 09/807,902

Group Art Unit: 2812

Filed: April 19, 2001

Examiner: Unknown

For: WAFER SUPPORT IN SEMICONDUCTOR PRODUCTION APPARATUS

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
Washington, DC 20231

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

RECEIVED  
SEP 21 2001  
TC 1700

Each non-English language reference was cited in a corresponding foreign application search report or office action and its relevance discussed therein. A copy of the foreign search report or office action, together with an English language version thereof, is attached for the Examiner's information. A copy of the International Preliminary Examination Report dated November 28, 2000 issued in the related PCT application is also attached hereto.

Respectfully submitted,

MCDERMOTT, WILL & EMERY



Stephen A. Becker  
Registration No. 26,527

600 13<sup>th</sup> Street, N.W.  
Washington, DC 20005-3096  
(202) 756-8000 SAB:MWE  
**Date: September 17, 2001**  
Facsimile: (202) 756-8087